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CCS L95

SJ

INDUSTRY STANDARD OF THE PEOPLE'S REPUBLIC OF CHINA

SJ 21131-2016

General specification for reactive ion etching machines

反应离子刻蚀机通用规范

(English Translation)

Issued by: Ministry of Industry and Information Technology

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1 Foreword

SJ 21131-2016 is issued by Ministry of Industry and Information Technology.

The SJ prefix, without a suffix, marks a mandatory standard: within its scope, compliance is required.

The document runs to 14 pages in English translation.

2 Scope Preview

SJ 21131-2016 is filed under Chinese Standard Classification L95, in the field of electronic components and information technology.

This catalogue holds 1,191 other SJ standards without an ICS number.

In this catalogue, SJ standards carry edition years from 1965 to 2021.

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3 About this standard

Sector: Electronics Industry Standard

Issued by: Ministry of Industry and Information Technology

English translation: about 14 pages (approximate)

Chinese original: about 20,289 characters

4 Related standards

Standards on related subjects:

GB/T 28159-2025 - Electronic grade phosphoric acid

SJ/T 11794-2022 - Test method for unbonded lithium of cathode materials used in lithium ion battery

SJ/T 11795-2022 - Test method for determining magnetic impurity content of electrode materials in lithium ion batteries

SJ 21128-2016 - General specification for horizontal plasma chemical vapor deposition equipment (PECVD)

SJ 21129-2016 - General specification for metal organic chemical vapor deposition equipment (MOCVD)

SJ 21130-2016 - General specification for plasma etching machines

5 Classification and status

Chinese Standard Classification (CCS): L 95

Prefix SJ: mandatory standard.

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